



Appl. No.:

10/054,697

Applicant:

Walitzki et al.

Filed:

January 18, 2002

TC/A.U.:

2822

Examiner

Guerrero, M.

Docket No.:

4451-24-1 (formerly 020016-000311US)

Customer No.:

22442

For:

FINISHING POLY-"METHOD FOR

SILICON OR AMORPHOUS SUBSTRATE

STRUCTURES"

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313

CERTIFICATE OF MAILING

Confirmation No. 5401

I HEREBY CERTIFY THAT THIS CORRESPONDENCE IS BEING DEPOSITED WITH THE UNITED STATES POSTAL SERVICE AS FIRST CLASS MAIL IN AN ENVELOPE ADDRESSED TO COMMISSIONER FOR PATENTS, P.O. BOX 1450, ALEXANDRIA VA 22313-1450 ON SEPTEMBER 15, 2003.

SHERIDAN ROSS P.C.

REQUEST FOR EXTENSION OF TIME

Dear Sir:

Applicants, through attorneys, respectfully petition for an extension of time under 37 CFR § 1.136(a) of three (3) months to respond to the Office Action mailed on March 13, 2003, with respect to the above-identified application, thereby extending the period for response from June 13, 2003, to September 13, 2003.

Enclosed is a check in the amount of \$465.00 as payment for the extension fee. Please credit any overpayment or debit any underpayment to Deposit Account No. 19-1970.

Respectfully submitted,

SHERIDAN ROSS P.C.

Robert D. Traver

Registration No. 47,999 1560 Broadway, Suite 1200

Denver, Colorado 80202-5141

(303) 863-9700

00000002 100\$4697 19/24/2003 ANABI1